Supplementary Information for

Precisely picking nanoparticles by ‘Nano-scalpel’ for 360⁰ Electron Tomography

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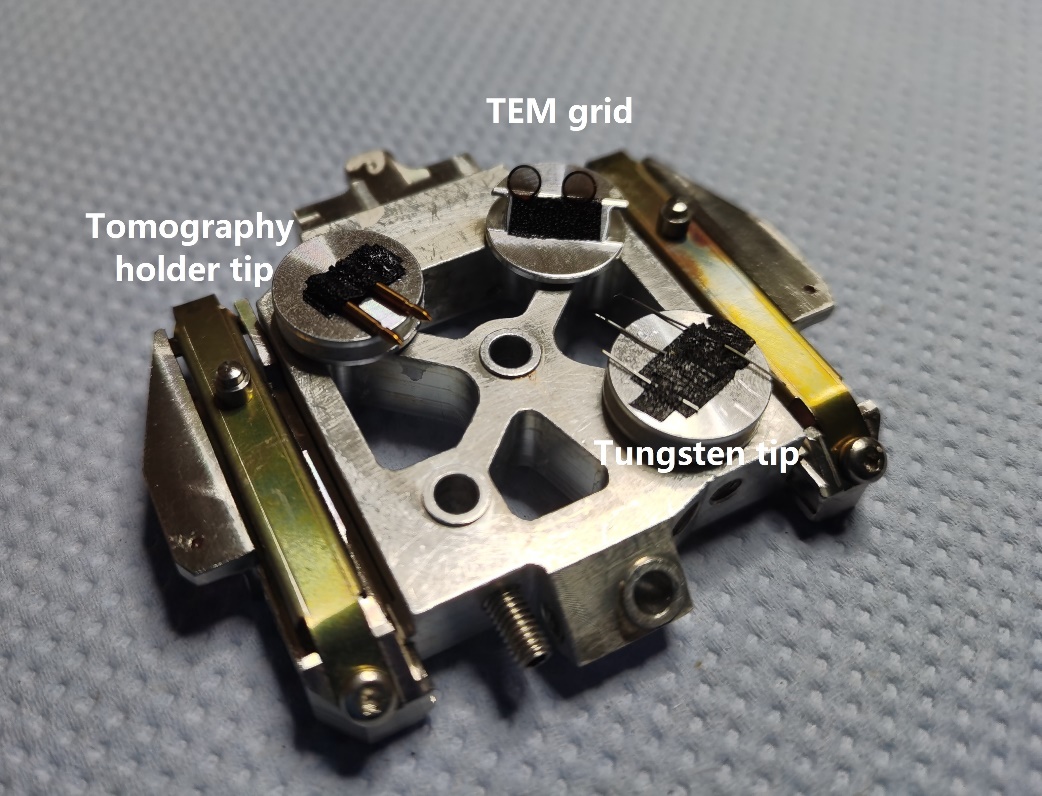
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**Figure S1.** Tungsten preparation by electrochemical etching.



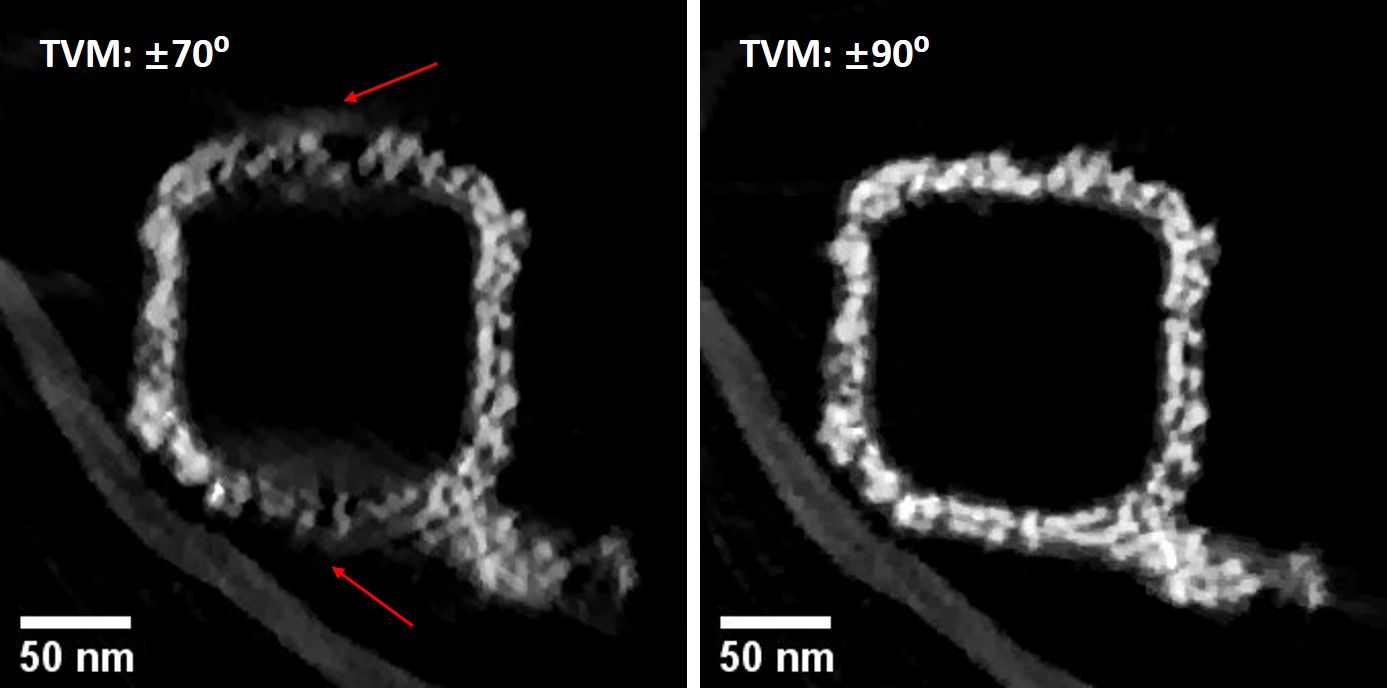
**Figure S2.** Scanning electron micrographs of etched tips.

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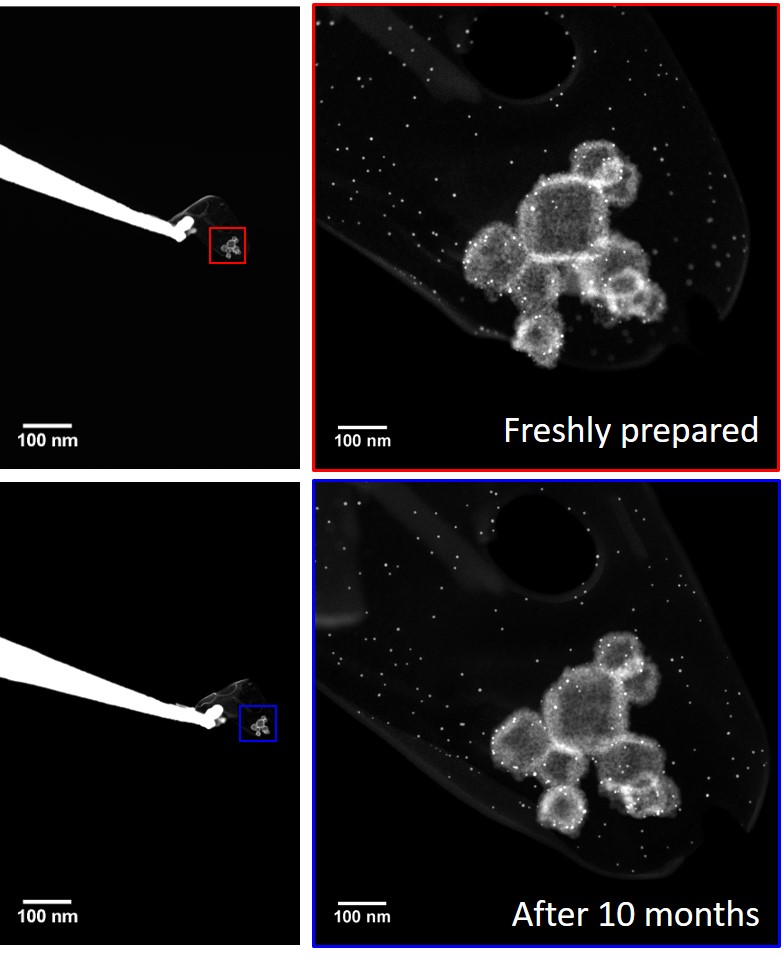
**Figure S3.** Initial FIB stage setup with tungsten tip, TEM grid and 360° tomography holder tip loaded on it.



**Figure S4.** Three commercial TEM grids covered by different carbon films including (a) 100×400 mesh carbon film (thickness: 10-20 nm), (b) 200 mesh holey carbon film (thickness: ~12 nm) with patterned holes and (c) 200 mesh lacey carbon film (thickness: ~20 nm) with irregular holes used for transferring tomography samples.

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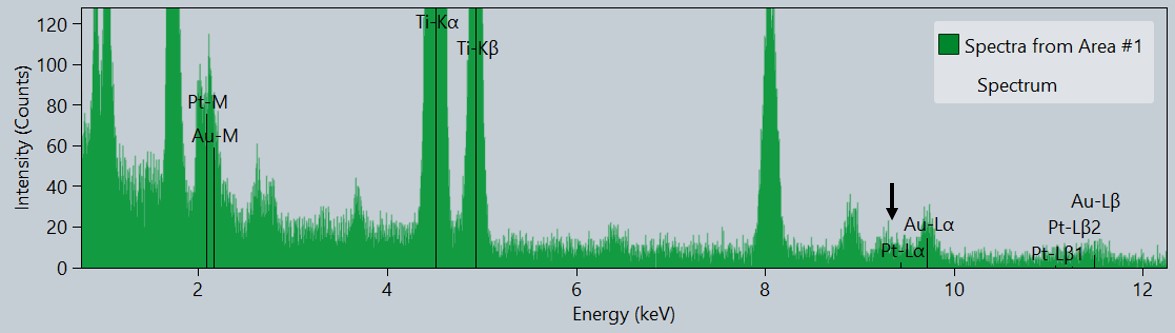
**Figure S5.** The representative yz slices from the dataset with limited angle range and full rotation using TVM reconstruction.

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**Figure S6.** STEM images showing stable sample form by comparing the freshly prepared sample and that after 10 months.



**Figure S7.** Representative slices from the aligned sinogram.



**Figure S8.** EDX spectrum acquired from the sample area after finishing the preparation.